

This listing of claims will replace all prior versions, and listings, of claims in the application:

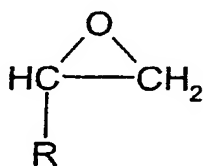
1.(Original) A process for preparing an alkylene glycol diether by reacting a linear or cyclic ether with an alkylene oxide in the presence of a Lewis acid, wherein the reaction is carried out continuously in a microreactor.

2.(Currently Amended) The process according to claim 1 wherein the alkylene glycol diether [[ether]] conforms to the formula



where R^1 is C_1 to C_{12} alkyl, R^2 is C_1 to C_{12} alkyl, phenyl or benzyl or wherein R^1 and R^2 combine to form a ring of 5, 6 or 7 atoms that encloses the oxygen atom.

3.(Currently Amended) The process according to claim 1, [[and/or 2]] wherein the alkylene oxide conforms to the formula



where R is H, halogen, C_1 to C_{10} alkyl, phenyl or benzyl.

4.(Currently Amended) The process of claim 1, ~~according to one or more of claims 1 to 3~~ wherein the Lewis acid is selected from the group consisting of metal and nonmetal halides, hydrogen acids, heteropolyacids, haloalkyls, ethers, acid

chlorides, acid esters, acid anhydrides, trialkyloxonium salt complexes having identical or different alkyl groups, acylium salt complexes, ~~and also~~ unsaturated tertiary oxonium salts, and mixtures thereof.

5.(Currently Amended) The process of claim 1, ~~according to one or more of claims 1 to 4~~ wherein the reacting step is carried out in a solvent is ~~utilized, said solvent being~~ selected from the group consisting of dichloromethane, nitromethane, benzene, toluene, acetone, ethyl acetate, dioxane, methanol, ethanol, propanol, butanol, methylglycol, methyldiglycol, methyltriglycol, ~~[[or]]~~ mono- glycol dimethyl ether, [[or]] polyalkylene glycol dimethyl ether, and mixtures thereof.

6.(Currently Amended) The process of claim 1, ~~according to one or more of claims 1 to 5~~ wherein the microreactor ~~[[used]]~~ has a reaction channel which is a capillary having a round cross section ~~[[and]]~~ said capillary having a diameter in the range from 400 to 1000 μm .